



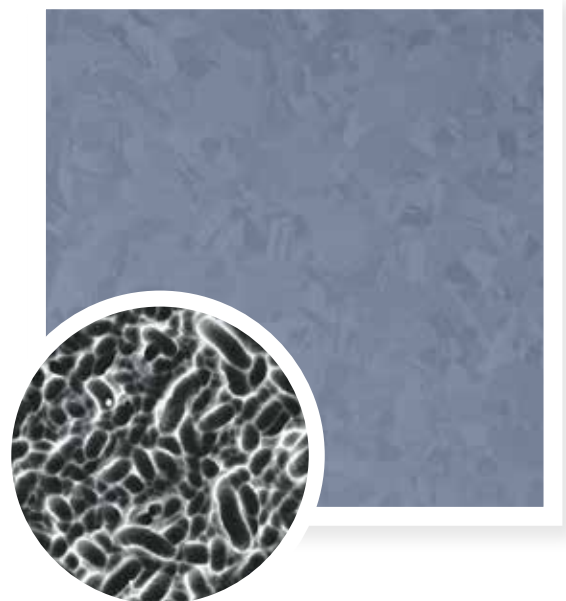
RCT i-Text

RCT i-Text is part of the RCT Inline machine family.

RCT i-Text is designed to remove the saw damage of multicrystalline wafers and textures the wafer surface for best antireflection behavior.

It is optimized for lowest CoO by low chemical consumption, stable processes and small footprint.

textured wafer



Highlights

- ✦ Advanced single-side texturing technology for 35% chemical and disposal cost saving available
- ✦ Advanced alkaline cleaning design to avoid KOH contamination
- ✦ Surface near frequent chemical exchange for high-performance metal impurity cleaning
- ✦ Unique quick-lock system of spray bars for easy and safety maintenance
- ✦ Up to 30% reduced DI water consumption due to improved rinse bath performance

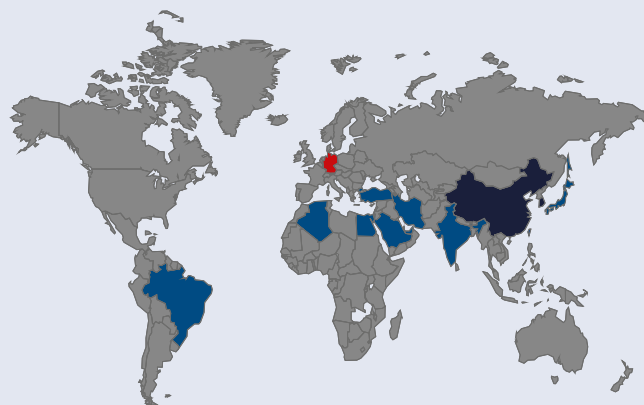


optimized hydrodynamics in metal impurity cleaning

RCT i-TEX Technical Data

| | |
|------------------|---|
| Process | Inline saw damage etch and acidic texturization |
| Throughput | 3,600 w/h gross, 5 lanes |
| Conveyor speed | 0.5 – 2.5 m/min, nominal 2.1 m/min |
| Dimensions | 8880 x 2200 x 2120 mm ³ (L x W x H) |
| Wafer size | 156 x 156 ± 0.75mm, ≥ 150 µm |
| Etch depth range | 4 – 6 µm |
| Bath lifetime | > 700,000 wafers |

RCT Solutions –
where we are



Headquarter

Constance, Germany

Affiliates & Offices

China

Taiwan

Korea

Sales Partner